

Materials List for:

Micro/Nano-scale Strain Distribution Measurement from Sampling Moiré Fringes

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Materials

Name	Company	Catalog Number	Comments
Automatic Polishing Machine	Marumoto Struers K.K.	LaboPol-30, Labor Force-100	
Carbon Fiber Reinforced Plastic	Mitsubishi Plastics, Inc.	HYEJ16M95DHX1	
Computer	DELL Japan	VOSTRO	Can be replaced with another computer with C++ programming language
Image Recording Software	Lasertec Corporation	LMEYE7	Installed in a laser scanning microscope
Ion Coater	Japan Electron Optics Laboratory Ltd.	JEC3000F	
Laser Scanning Microscope	Lasertec Corporation	OPTELICS HYBRID	
Nanoimprint Device	Japan Laser Corporation	EUN-4200	Can be replaced with a electron beam lithography device or a focused ion beam milling device
Nanoimprint Mold	SCIVAX Corporation	3.0µm pitch	Customized
Nanoimprint Resist	Toyo Gosei Co., Ltd	PAK01	
Polishing Solution	Marumoto Struers K.K.	DP-Spray P 15µm, 1µm, 0.25µm	Use from coarse to fine
Pipet	AS ONE Corporation	10mL	
Sand Paper	Marumoto Struers K.K.	SiC Foil #320, #800	Use from coarse to fine
Spin Coater	MIKASA Corporation	MS-A100	